

Ref #	Hits	Search Query	DBs	Default Operator	Plurals	Time Stamp
S87	22	("20020075094" "20020096421" "20020124385" "20030047799" "5367585" "5479042" "5544001" "5619061" "5959338" "6133807" "6153839" "6160230" "6307452" "6366186" "6426687" "6440767" "6472962" "6535091" "6621387").PN. OR ("6713695").URPN.	US-PGPUB; USPAT; USOCR	OR	ON	2005/08/17 13:57
S86	3	("20020145493" "6307452" "6486425").PN. OR ("6806545").URPN.	US-PGPUB; USPAT; USOCR	OR	ON	2005/08/17 13:56
S85	25	("5578976" "5619061" "5880921").PN. OR ("6307452").URPN.	US-PGPUB; USPAT; USOCR	OR	ON	2005/08/17 12:47
S84	306	(microelectromechanical or micro-electromechanical or micro-electro-mechanical or mems or microactuator) and sun.inv.	US-PGPUB; USPAT; EPO; JPO; DERWENT; IBM_TDB	OR	ON	2005/08/17 12:44
S83	22	(microelectromechanical or micro-electromechanical or micro-electro-mechanical or mems or microactuator) and S81	US-PGPUB; USPAT; EPO; JPO; DERWENT; IBM_TDB	OR	ON	2005/08/17 12:44
S82	0	S80 and S81	US-PGPUB; USPAT; EPO; JPO; DERWENT; IBM_TDB	OR	ON	2005/08/17 12:33
S81	31	"actuation electrode" and "signal electrode"	US-PGPUB; USPAT; EPO; JPO; DERWENT; IBM_TDB	OR	ON	2005/08/17 12:33
S79	974	(microelectromechanical or micro-electromechanical or micro-electro-mechanical or mems or microactuator) and shunt	US-PGPUB; USPAT; EPO; JPO; DERWENT; IBM_TDB	OR	ON	2005/08/17 12:33
S80	727	S79 and (beam membrane)	US-PGPUB; USPAT; EPO; JPO; DERWENT; IBM_TDB	OR	ON	2005/08/17 12:32

S78	387	(microelectromechanical or micro-electromechanical or micro-electro-mechanical or mems or microactuator) and shunt and rf	US-PGPUB; USPAT; EPO; JPO; DERWENT; IBM_TDB	OR	ON	2005/08/17 12:32
S67	3040	(microelectromechanical or micro-electromechanical or micro-electro-mechanical or mems or microactuator) and electrostatic and dielectric	US-PGPUB; USPAT; EPO; JPO; DERWENT; IBM_TDB	OR	ON	2005/08/17 12:31
S77	72	S75 and S76	US-PGPUB; USPAT; EPO; JPO; DERWENT; IBM_TDB	OR	ON	2005/08/15 11:42
S76	926	335/78.ccls. 200/181.ccls.	US-PGPUB; USPAT; EPO; JPO; DERWENT; IBM_TDB	OR	ON	2005/08/15 11:42
S75	1469	(microelectromechanical or micro-electromechanical or micro-electro-mechanical or mems or microactuator) and beam and S74	US-PGPUB; USPAT; EPO; JPO; DERWENT; IBM_TDB	OR	ON	2005/08/15 11:42
S74	132070	(contact electrode) same(metal\$4 adj (layer contact film))	US-PGPUB; USPAT; EPO; JPO; DERWENT; IBM_TDB	OR	ON	2005/08/15 11:42
S73	60426	electrode same(metal\$4 adj (layer contact film))	US-PGPUB; USPAT; EPO; JPO; DERWENT; IBM_TDB	OR	ON	2005/08/15 11:42